

**10/565879**

1AP20 Rec'd PCT/PTO 23 JAN 2006

ATTORNEY DOCKET NO: 72096

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : TAKAMATSU  
PCT No. : PCT/JP2004/009731  
Confirm. No. : N/A  
Filed : January 23, 2006  
For : WAFER POLISHING METHOD  
Art Unit : N/A  
Examiner : N/A  
Dated : January 23, 2006

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

The following references have been cited in the International Phase of the above-identified application.

- JP 2002-190458 discloses a water dispersion for chemical mechanical polishing. The reference has been cited under Category Y as being relevant to International claims 1, 4 and 7 - 17 and further cited under Category A as being relevant to International claims 2, 3, 5 and 6. No full translation is available at this time, however, attached is an English language abstract.

- JP 11-111657 discloses a polishing liquid and polishing method. The reference has been cited under Category Y as being relevant to International claims 1, 4 and 7 - 17 and further cited under Category A as being relevant to International claims 2, 3, 5 and 6. No full translation is available at this time, however, attached is an English language abstract.

- JP 63-74911 discloses a production of fine spherical silica. The reference has been

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cited under Category Y as being relevant to International claims 1, 4 and 7 - 17 and further cited under Category A as being relevant to International claims 2, 3, 5 and 6. No full translation is available at this time, however, attached is an English language abstract. Applicant further wishes to bring to the attention of the Examiner the corresponding U.S. Patent 4,842,837.

- JP 2002-252189 discloses a polishing liquid for semiconductor wafer. The reference has been cited under Category Y as being relevant to International claim 8. No full translation is available at this time, however, attached is an English language abstract.

Consideration of the above references is requested.

Respectfully submitted  
for Applicant,

By:

  
John James McGlew  
Registration No. 31,903  
McGLEW AND TUTTLE, P.C.

JJM:tf  
72096.5

Enclosed: PTO-1449 Form  
copy of International Search Report  
copies of (4) References

DATED: January 23, 2006  
SCARBOROUGH STATION  
SCARBOROUGH, NEW YORK 10510-0827  
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SHOULD ANY OTHER FEE BE REQUIRED, THE PATENT AND TRADEMARK OFFICE IS HEREBY REQUESTED TO CHARGE SUCH FEE TO OUR DEPOSIT ACCOUNT 13-0410.

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AP20R-110710 23 JAN 2006

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BY: *Jonathan Fonte* DATE: January 23, 2006

Form PTO-1449

U.S. Department of Commerce Sheet 1 of 1  
Patent and Trademark Office

LIST OF REFERENCES CITED  
BY APPLICANT  
(Use several sheets if necessary)

Atty Docket No.: 72096  
PCT No.: PCT/JP2004/009731  
Applicant: TAKAMATSU

U.S. PATENT DOCUMENTS

Ex- aminer Initial	Document No.	Date	Name	Class	Sub- class	Filing Date
	<u>4,842,837</u>	<u>June 27, 1989</u>	<u>Shimizu et al.</u>			<u>Sept. 18, 1987</u>

FOREIGN PATENT DOCUMENTS

Ex- aminer Initial	Document No.	Date	Country	Class	Sub- class	Translation Yes/No
	<u>JP 2002-190458</u>	<u>July 5, 2002</u>	<u>Japan</u>			<u>No</u>
	<u>JP 11-111657</u>	<u>April 23, 1999</u>	<u>Japan</u>			<u>No</u>
	<u>JP 63-74911</u>	<u>April 5, 1988</u>	<u>Japan</u>			<u>No</u>
	<u>JP 2002-252189</u>	<u>Sept., 6, 2002</u>	<u>Japan</u>			<u>No</u>

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

Ex- aminer Initial	Author	Date	Title	Textbook in	Translation Yes/No

\_\_\_\_\_  
Examiner

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Date Considered